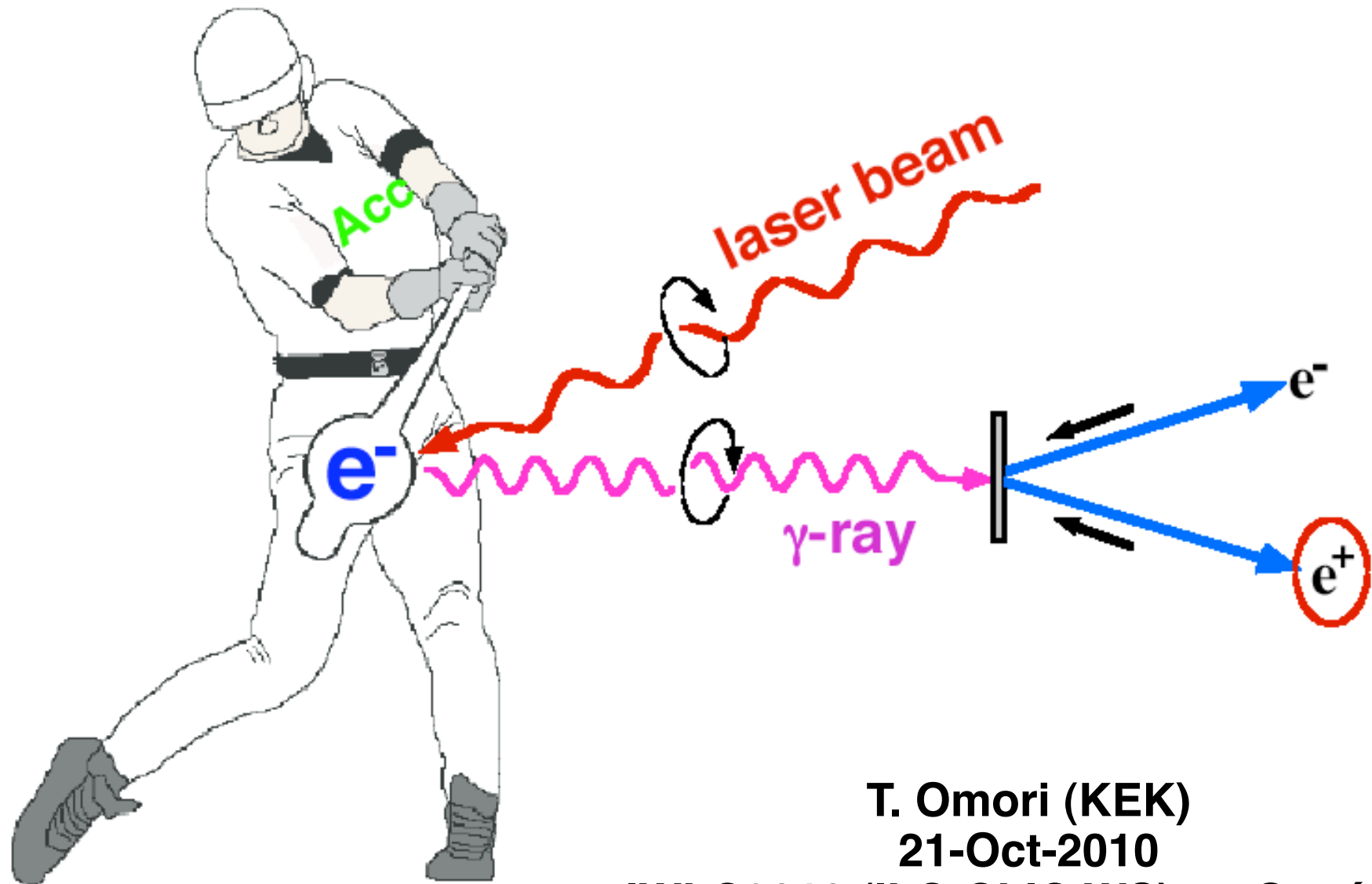


Ring/ERL Compton e^+ Source for ILC/CLIC



T. Omori (KEK)

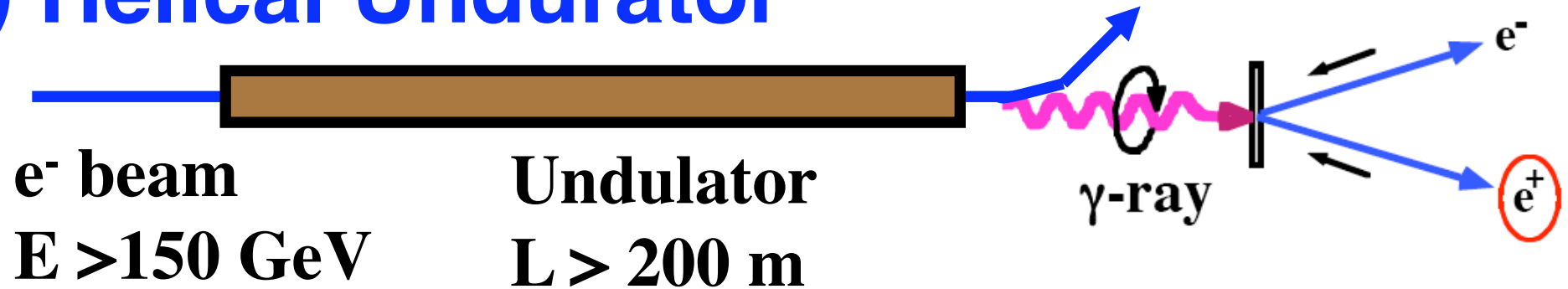
21-Oct-2010

IWLC2010 (ILC-CLIC WS) at Genève

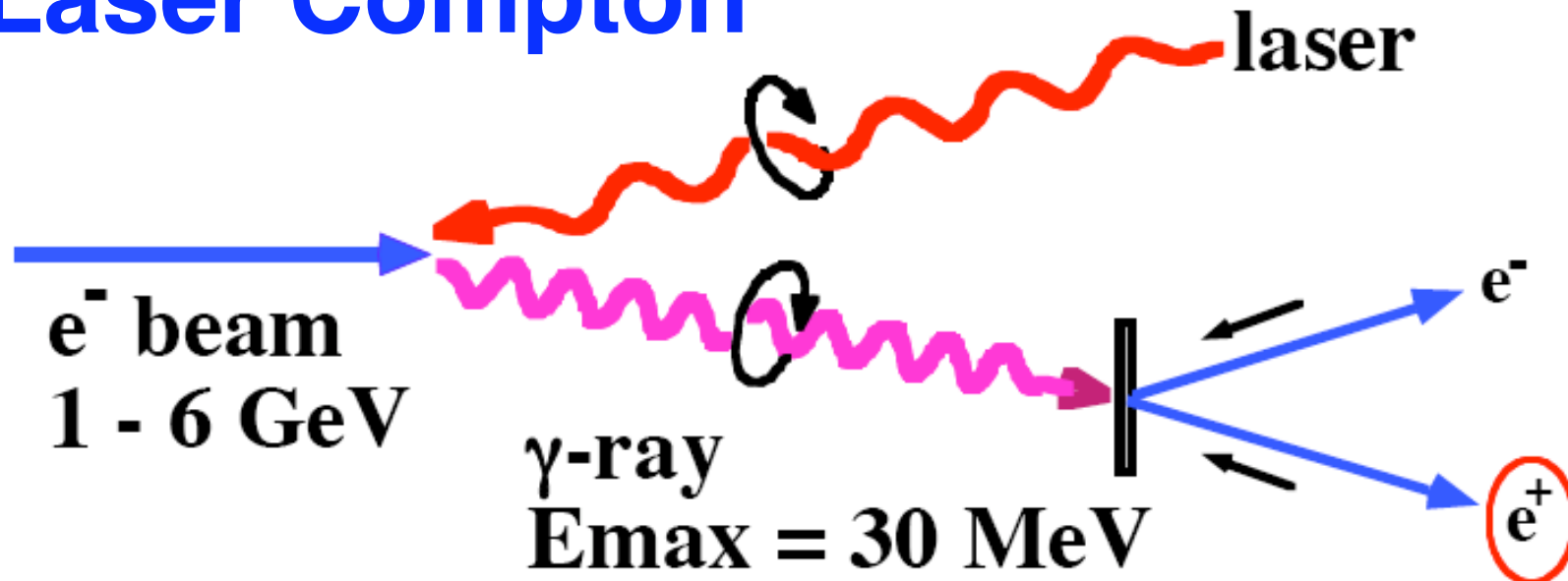
Laser-Compton e^+ source for ILC/CLIC

Two ways to get pol. e^+

(1) Helical Undulator

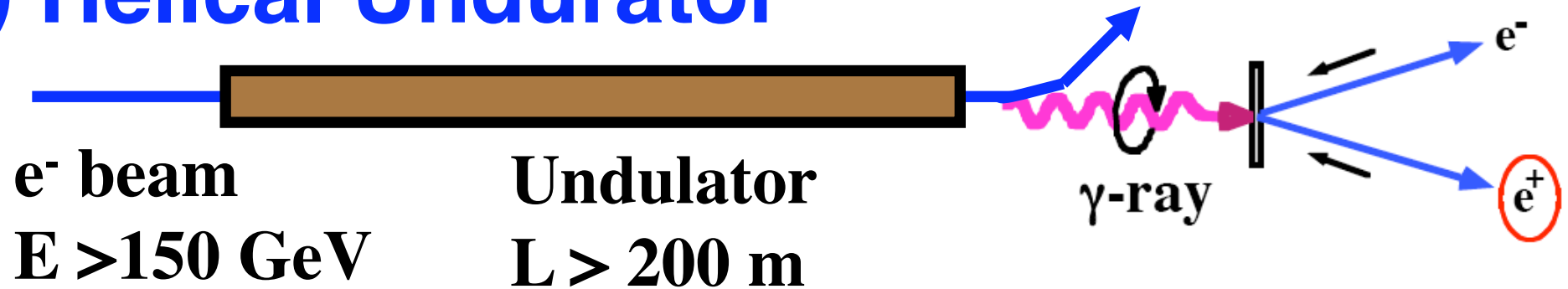


(2) Laser Compton



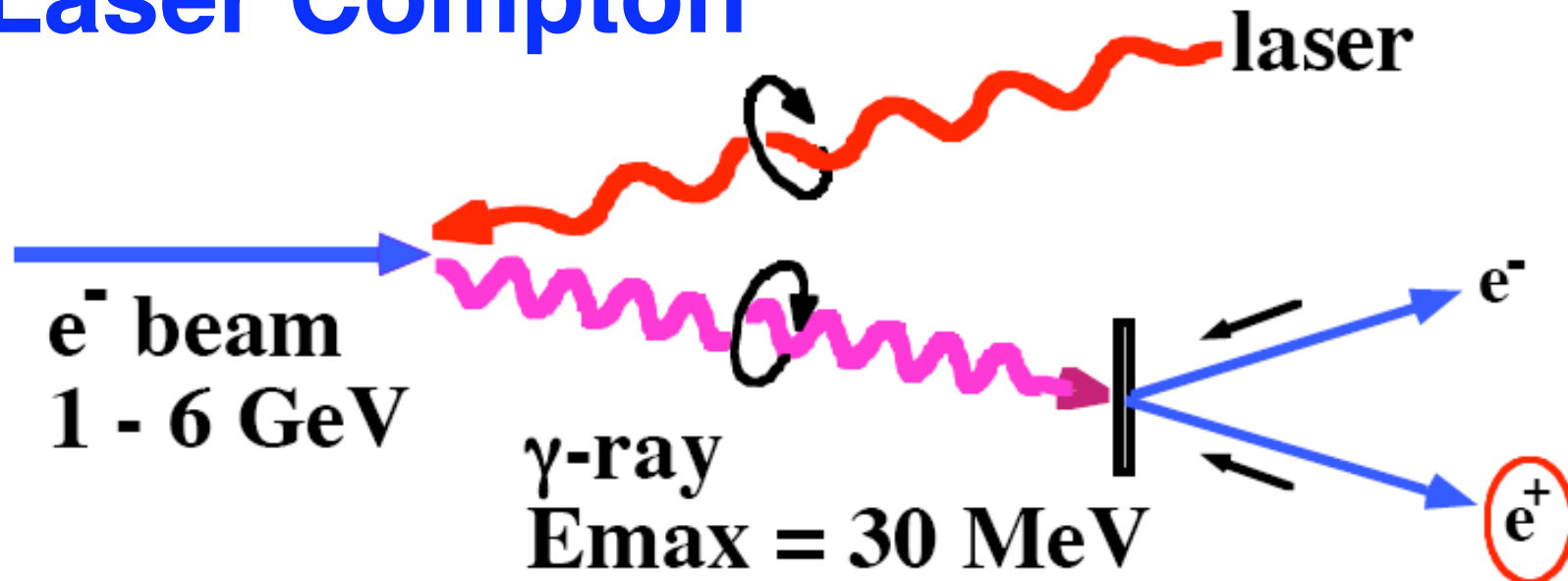
Two ways to get pol. e^+

(1) Helical Undulator



Our Proposal

(2) Laser Compton



Why Laser-Compton ?

i) Positron Polarization.

ii) Independence

Undulator-base e^+ : use e^- main linac

Problem on design, construction,
commissioning, maintenance,

Laser-base e^+ : independent

**Easier construction, operation,
commissioning, maintenance**

iii) Polarization flip @ 5Hz (for CLIC @ 50 Hz)

iv) High polarization

v) Low energy operation

Undulator-base e^+ : need deceleration

Laser-base e^+ : no problem

Status of Compton scheme

Proof-of-Principle demonstration was done.

ATF-Compton Collaboration

Polarized γ -ray generation: M. Fukuda et al., PRL 91(2003)164801

Polarized e⁺ generation: T. Omori et al., PRL 96 (2006) 114801

Status of Compton scheme

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**We still need many R/Ds and simulations.
Many Talks in this Workshop**

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Polarized e⁺ generation: T. Omori et al., PRL 96 (2006) 114801

**We still need many R/Ds and simulations.
Many Talks in this Workshop**

We have 3 schemes.

Choice 1 : How to provide e- beam

Storage Ring, ERL, Linac

Choice 2 : How to provide laser beam

Wave length ($\lambda=1\mu\text{m}$ or $\lambda=10\mu\text{m}$)

staging cavity or non staging cavity

Choice 3 : e⁺ stacking in DR or Not

Laser Compton e^+ Source for ILC/CLIC

We have 3 schemes.

1. Ring Base Laser Compton

**Storage Ring + Laser Stacking Cavity ($\lambda=1\mu\text{m}$),
and e^+ stacking in DR**

S. Araki et al., physics/0509016

2. ERL Base Laser Compton

**ERL + Laser Stacking Cavity ($\lambda=1\mu\text{m}$),
and e^+ stacking in DR**

3. Linac Base Laser Compton

talk: V. Yakimenko

**Linac + non-stacking Laser Cavity ($\lambda=10\mu\text{m}$),
and No stacking in DR**

Proposal V. Yakimenko and I. Pogorersky

T. Omori et al., Nucl. Instr. and Meth. in Phys. Res., A500 (2003) pp 232-252

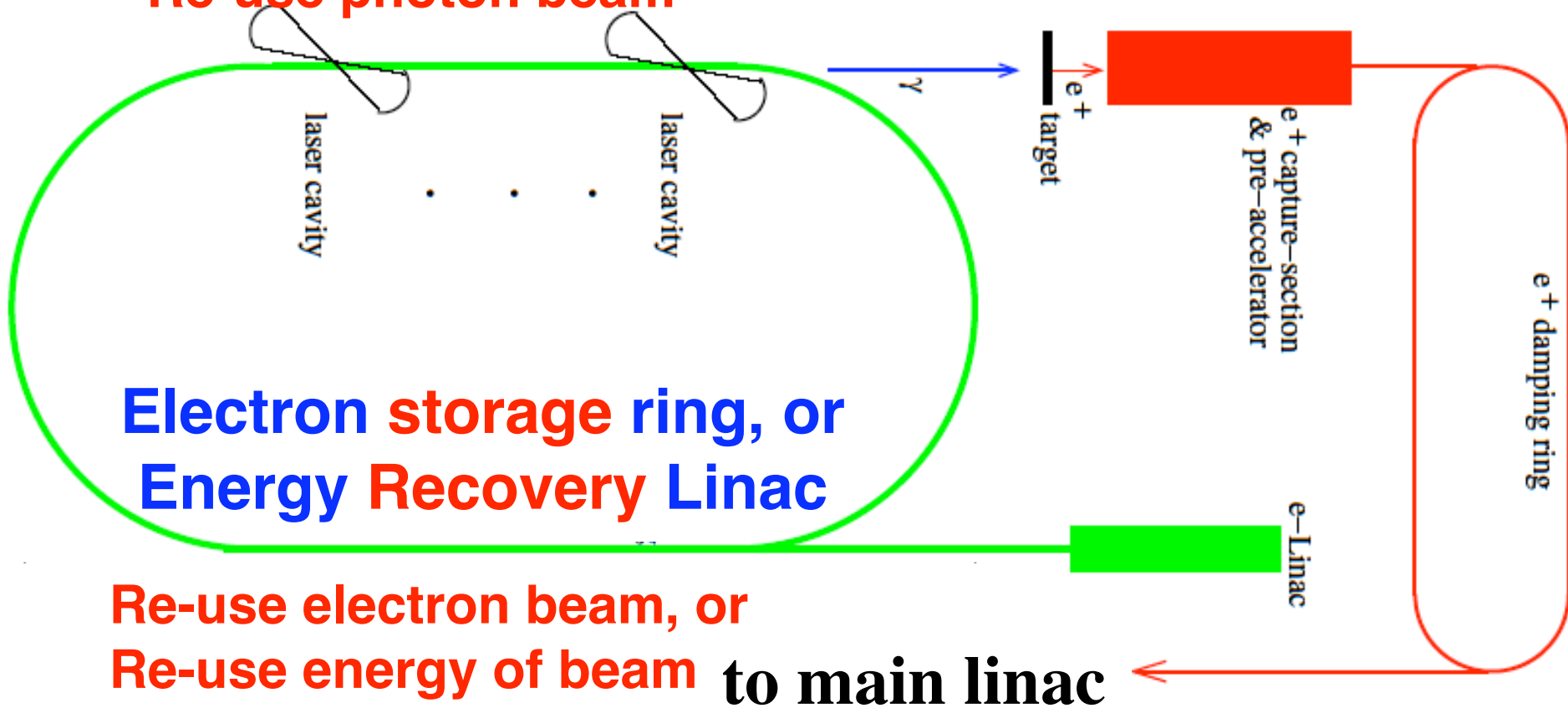
Good! But we have to choose!

Ring/ERL Scheme

Ring/ERL Compton Re-use Concept

laser pulse stacking optical cavities

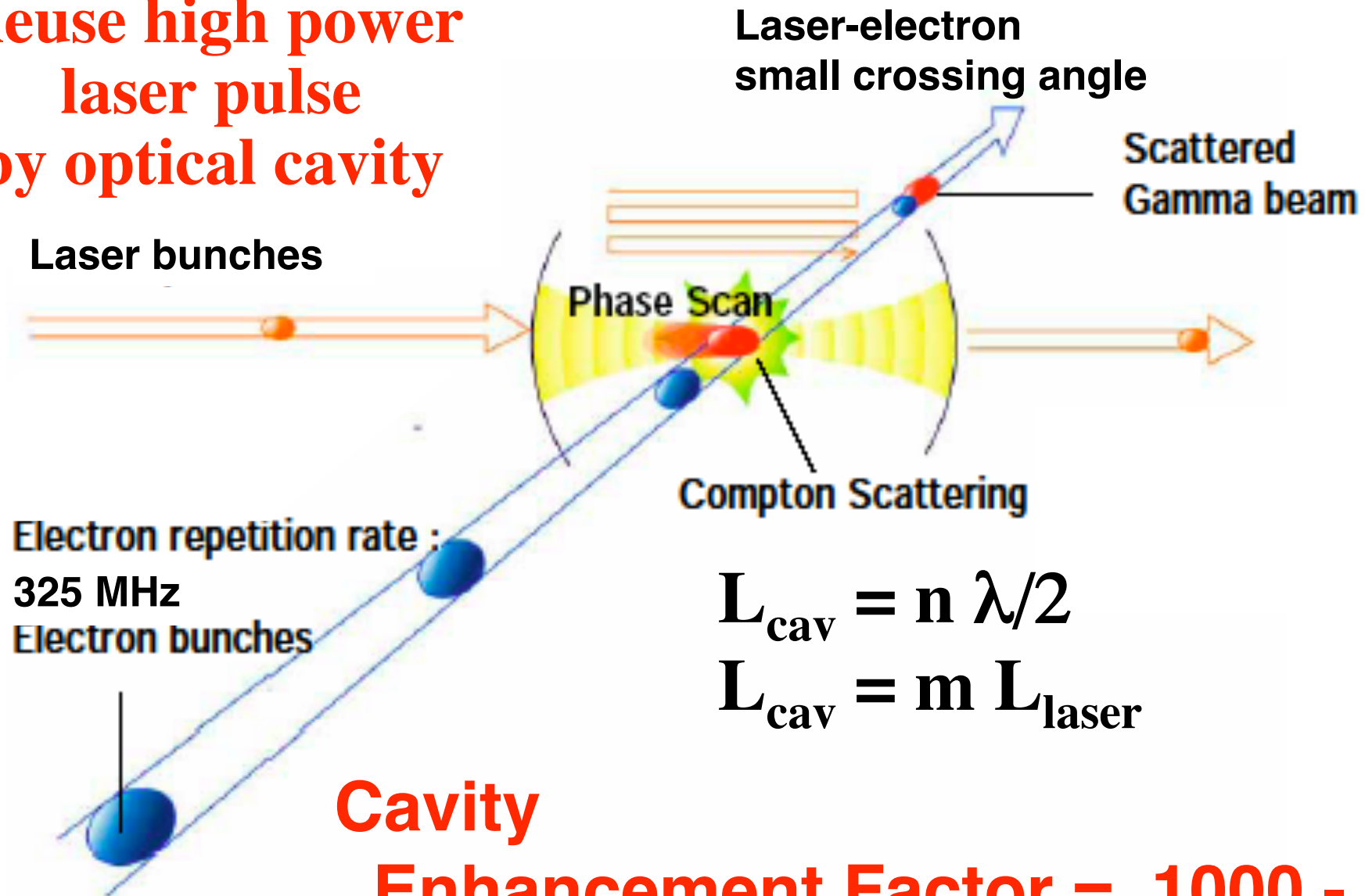
Re-use photon beam



positron stacking in main DR

Optical Cavity for Pulse Laser Beam Stacking

Reuse high power
laser pulse
by optical cavity

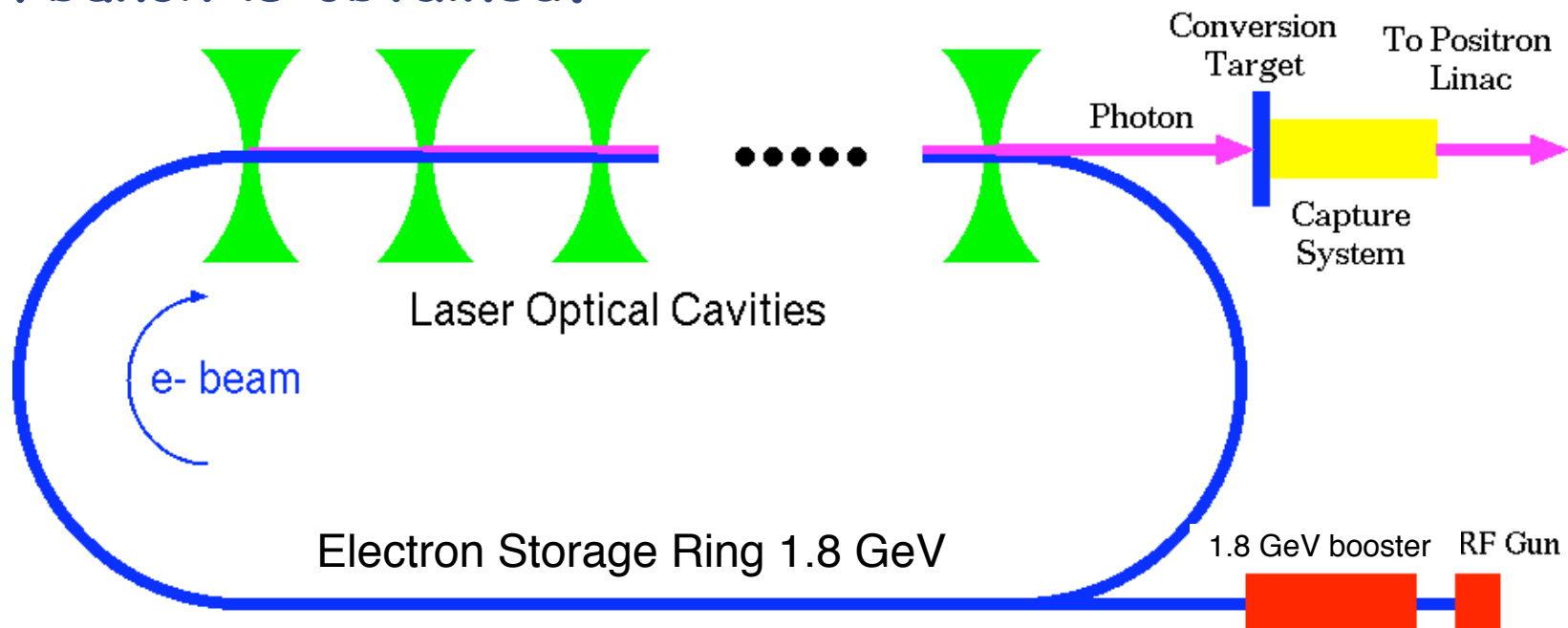


$$L_{\text{cav}} = n \lambda / 2$$

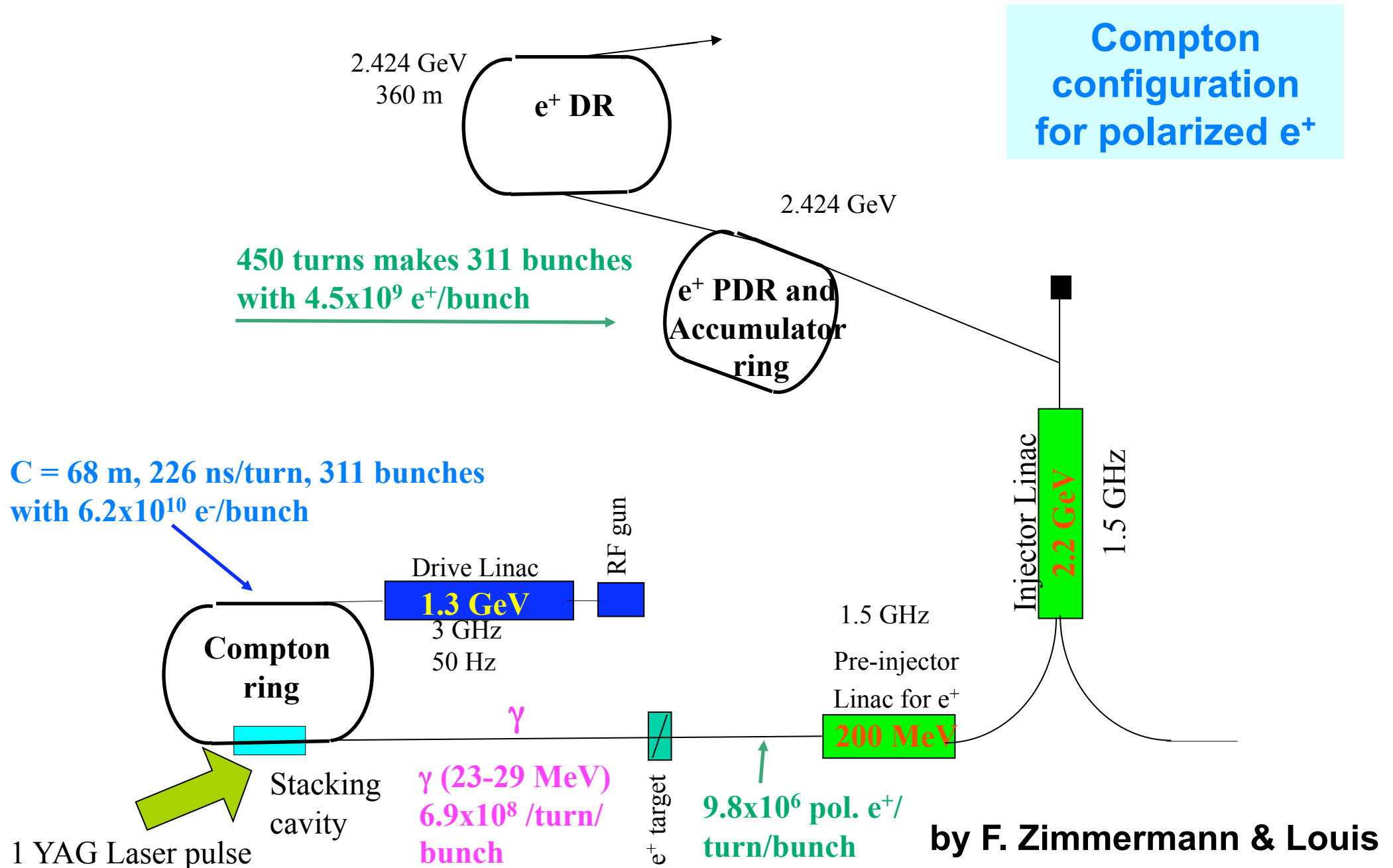
$$L_{\text{cav}} = m L_{\text{laser}}$$

Compton Ring Scheme for ILC

- ▶ Compton scattering of e⁻ beam stored in storage ring off laser stored in Optical Cavity.
- ▶ 5.3 nC 1.8 GeV electron bunches × 5 of 600mJ stored laser → $2.3\text{E}+10$ γ rays/bunch → $2.0\text{E}+8$ e⁺/bunch.
- ▶ 10 bunches are stacked on a same bucket. This is repeated 10 times with 10 ms interval.
- ▶ By stacking 100 bunches on a same bucket in DR, $2.0\text{E}+10$ e⁺/bunch is obtained.

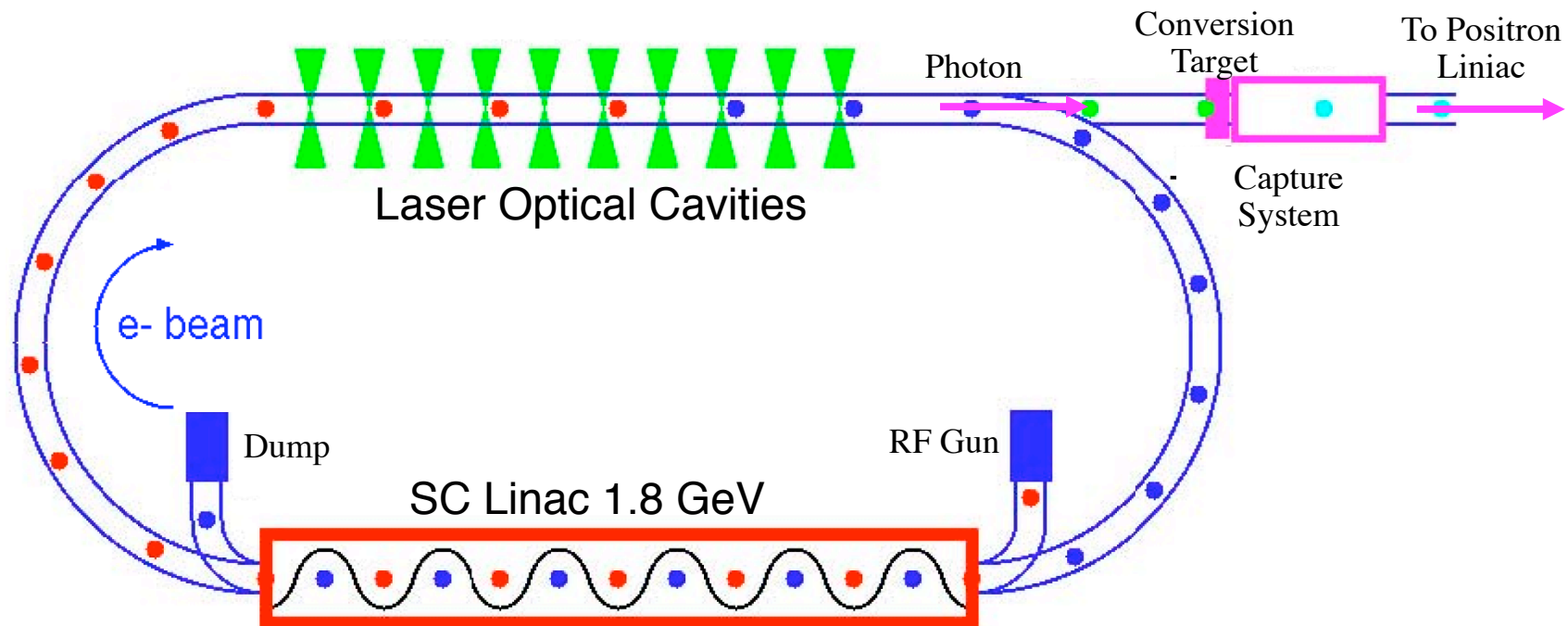


Compton Ring Scheme for CLIC



Compton ERL scheme for ILC

- High yield + high repetition in ERL solution.
 - 0.48 nC 1.8 GeV bunches x 5 of 600 mJ laser, repeated by 54 MHz \rightarrow $2.5\text{E}+9$ γ -rays \rightarrow $2\text{E}+7$ e^+ .
 - Continuous stacking the e^+ bunches on a same bucket in DR during 100ms, the final intensity is $2\text{E}+10$ e^+ .
- 1000 times of stacking in a same bunch



Choice of ERL parameters

I = 26 mA

(a) Ne/bunch = 1×10^9 $T_{b_to_b} = 6.15 \text{ ns}$ (160 pC x 160 MHz)

→ (b) Ne/bunch = 3×10^9 $T_{b_to_b} = 18.5 \text{ ns}$ (480 pC x 54 MHz)

prev.
page (c) Ne/bunch = 1×10^{10} $T_{b_to_b} = 61.5 \text{ ns}$ (1.6 nC x 16 MHz)

(d) Ne/bunch = 3×10^{10} $T_{b_to_b} = 185 \text{ ns}$ (4.8 nC x 5.4 MHz)

I = 80 mA (too ambitious !?)

(e) Ne/bunch = 3×10^9 $T_{b_to_b} = 6.15 \text{ ns}$ (480 pC x 160 MHz)

(f) Ne/bunch = 1×10^{10} $T_{b_to_b} = 18.5 \text{ ns}$ (1.5 nC x 54 MHz)

(g) Ne/bunch = 3×10^{10} $T_{b_to_b} = 61.5 \text{ ns}$ (4.8 nC x 16 MHz)

Choice of ERL parameters

ERL

I = 26 mA

- | | | |
|-----------------------------------|-------------------------|--------------------|
| (a) Ne/bunch = 1×10^9 | $T_{b_to_b} = 160$ ns | (160 pC x 160 MHz) |
| (b) Ne/bunch = 3×10^9 | $T_{b_to_b} = 1$ s | (480 pC x 54 MHz) |
| (c) Ne/bunch = 1×10^{10} | $T_{b_to_b} = 6$ s | (1.6 nC x 16 MHz) |
| (d) Ne/bunch = 3×10^{10} | $T_{b_to_b} = 18$ s | (4.8 nC x 5.4 MHz) |

more difficult

I = 80 mA (too ambitious !?)

- | | | |
|-----------------------------------|-------------------------|--------------------|
| (e) Ne/bunch = 3×10^9 | $T_{b_to_b} = 160$ ns | (480 pC x 160 MHz) |
| (f) Ne/bunch = 1×10^{10} | $T_{b_to_b} = 1$ s | (1.5 nC x 54 MHz) |
| (g) Ne/bunch = 3×10^{10} | $T_{b_to_b} = 6$ s | (4.8 nC x 16 MHz) |

more difficult

Choice of ERL parameters

I = 26 mA

	ERL	Laser & Stacking
(a) Ne/bunch = 1×10^9	$T_{b_to_b} = 160 \text{ ns}$	(160 pA, 60 MHz)
(b) Ne/bunch = 3×10^9	$T_{b_to_b} = 1 \text{ ns}$	(480 pA, 54 MHz)
(c) Ne/bunch = 1×10^{10}	$T_{b_to_b} = 6 \text{ ns}$	(1.6 nA, 16 MHz)
(d) Ne/bunch = 3×10^{10}	$T_{b_to_b} = 18 \text{ ns}$	(4.8 nA, 5.4 MHz)

ERL

more difficult

Laser & Stacking

Easier

I = 80 mA (too ambitious !?)

(e) Ne/bunch = 3×10^9	$T_{b_to_b} = 480 \text{ ns}$	(480 pA, 160 MHz)
(f) Ne/bunch = 1×10^{10}	$T_{b_to_b} = 1 \text{ ns}$	(1.5 nA, 54 MHz)
(g) Ne/bunch = 3×10^{10}	$T_{b_to_b} = 4.8 \text{ ns}$	(4.8 nA, 16 MHz)

more difficult

Easier

Choice of ERL parameters

I = 26 mA

	ERL	Laser & Stacking
(a) Ne/bunch = 1×10^9	$T_{b_to_b} = 160 \text{ ns}$	(160 pA, 60 MHz)
(b) Ne/bunch = 3×10^9	$T_{b_to_b} = 1 \text{ ns}$	(480 pA, 54 MHz)
(c) Ne/bunch = 1×10^{10}	$T_{b_to_b} = 6 \text{ ns}$	(1.6 nA, 16 MHz)
(d) Ne/bunch = 3×10^{10}	$T_{b_to_b} = 18 \text{ ns}$	(4.8 nA, 5.4 MHz)

more difficult

Easier

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(g) Ne/bunch = 3×10^{10}	$T_{b_to_b} = 4.8 \text{ ns}$	(4.8 nA, 16 MHz)

more difficult

Easier

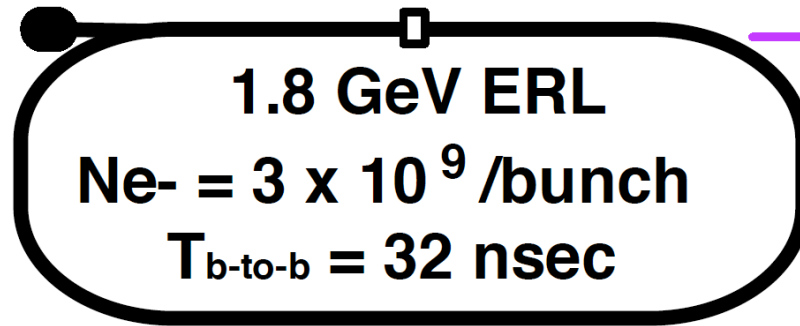
Note: Goal of KEK ERL project: E=5GeV, I=100 mA

Compton ERL scheme for CLIC

Louis&TO

Laser Pulse Stacking Cavity (YAG)

600 mJ x 1



Collision CW

gamma

$N_g = 5 \times 10^8$
 /circulation
 /bunch



$N_{e^+} = 2.5 \times 10^6$ /bunch

e^+
 $N_{e^+}/N_g = 0.5\%$

CW Linac
 $E = 1$ GeV
 (possible?)

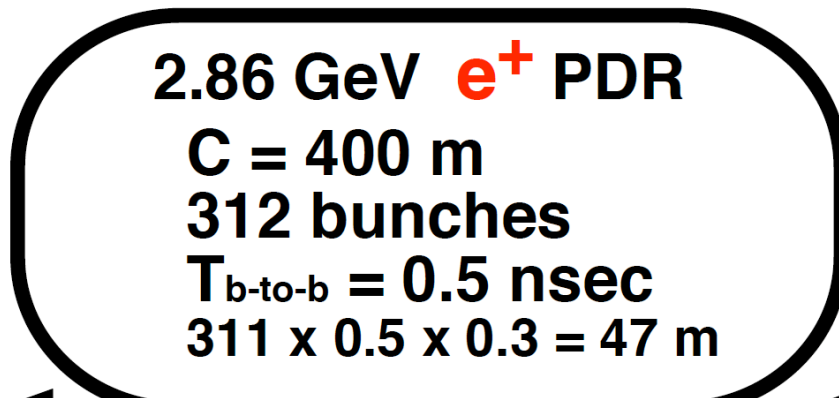
n-th cycle

SR1:stacking, SR2:damping

(n+1)th cycle

SR1:dampnig, SR2:staking

No Stacking in PDR



SR1

SR2

2 Stacking Rings

$C = 48$ m

321 bunches / ring

$T_{b-to-b} = 0.5$ nsec

$E = 1$ GeV

$321 \times 0.5 \times 0.3 = 48$ m

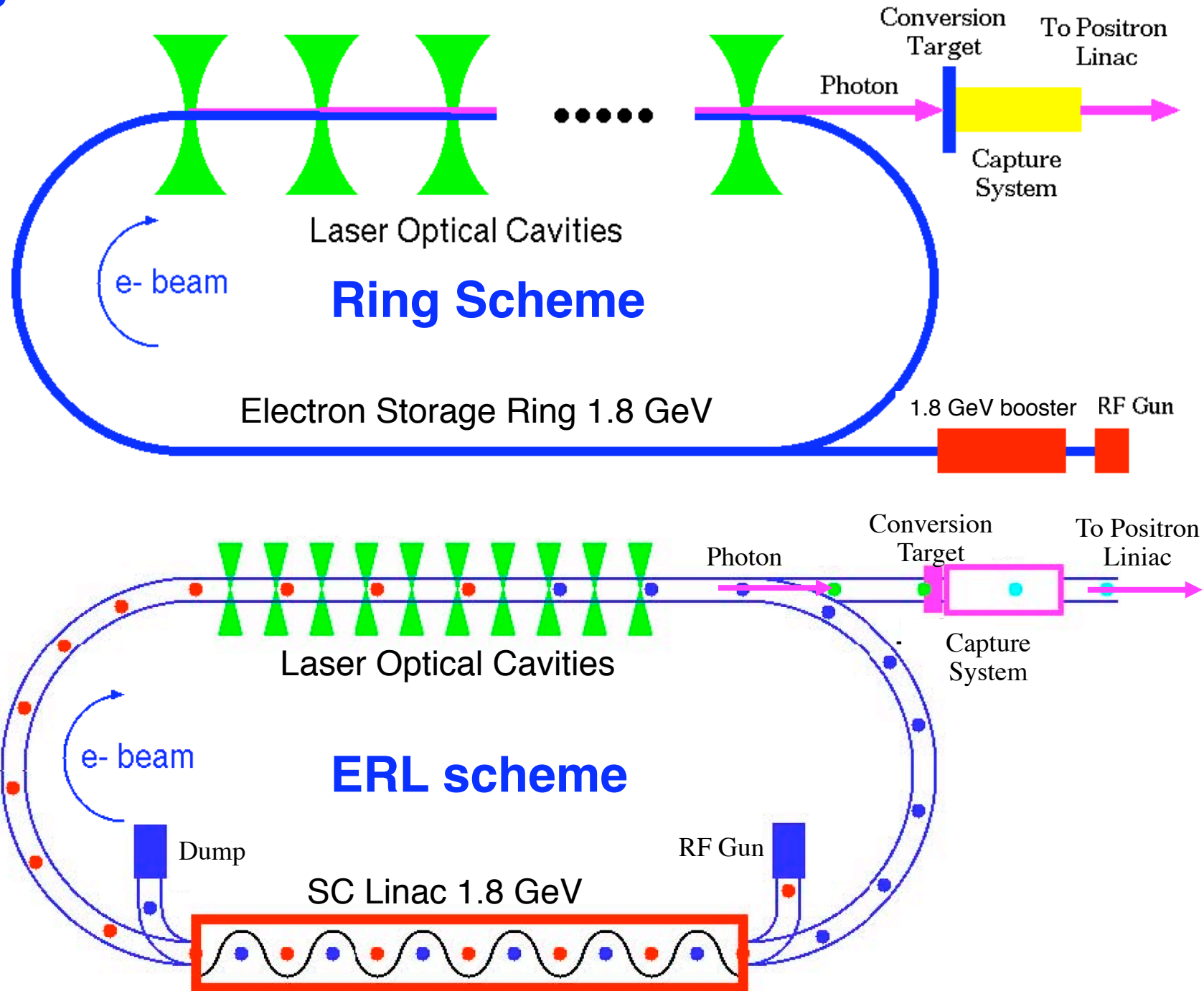
N of Stak = 2003

$N_{e^+} = 5 \times 10^9$ /bunch

50 Hz Linac
 $E = 1.86$ GeV

throw away 9 bunches

Ring scheme and ERL scheme are **SIMILAR**



What is the Difference? : Ring and ERL

What is Reused

Ring: Electron Beam

ERL: Energy of the electron beam

What is the Difference? : Ring and ERL

What is Reused

Ring: Electron Beam

ERL: Energy of the electron beam

Operation

Ring: Burst Operation (need cooling time)

ERL: as CW as possible

What is the Difference? : Ring and ERL

What is Reused

Ring: Electron Beam

ERL: Energy of the electron beam

Operation

Ring: Burst Operation (need cooling time)

ERL: as CW as possible

Bunch Length

Ring: Naturally Long (typically 30 psec)

ERL: Short (can be less than 1 p sec)

What is the Difference? : Ring and ERL

What is Reused

Ring: Electron Beam

ERL: Energy of the electron beam

Operation

Ring: Burst Operation (need cooling time)

ERL: as CW as possible

Bunch Length

Ring: Naturally Long (typically 30 psec)

ERL: Short (can be less than 1 p sec)

Bunch Charge

Ring: Larger

ERL: Smaller

Necessary R/Ds

for Ring/ERL scheme

Ring/ERL scheme R&D List

**e+ stacking in DR
simulation studies**

talks F. Zimmermann, E. Bulyak

CR simulation studies

talk E. Bulyak

ERL simulation studies

talk I. Chaikovska

e+ capture (common in all e+ sources)

Simulation study

talk A. Vivoli

Collaboration with KEKB upgrade

talk T. Kamitani

e+ production target

Laser

Fiber laser / Mode-lock laser

talks F. Zomer and J. Urakawa

Laser Stacking Cavity

**experimental and
theoretical studies**

talks F. Zomer and myself

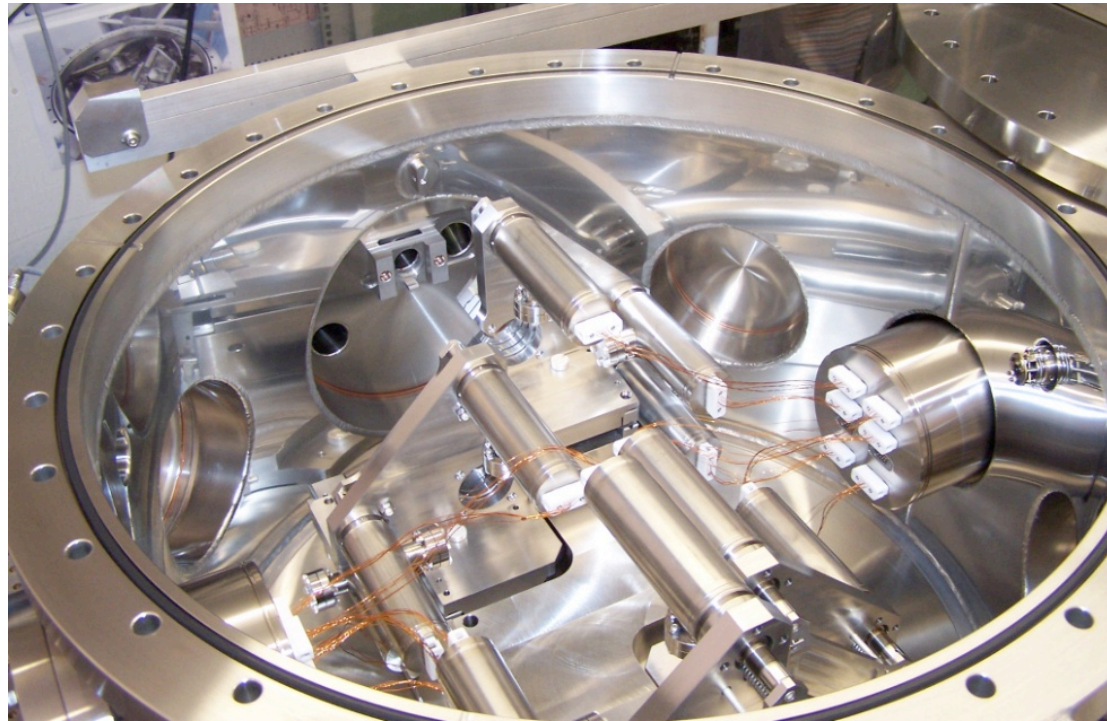
Just Example Prototype Cavities

2-mirror cavity (Hiroshima / Weseda /
Kyoto / IHEP / KEK)



**moderate enhancement
moderate spot size
simple control**

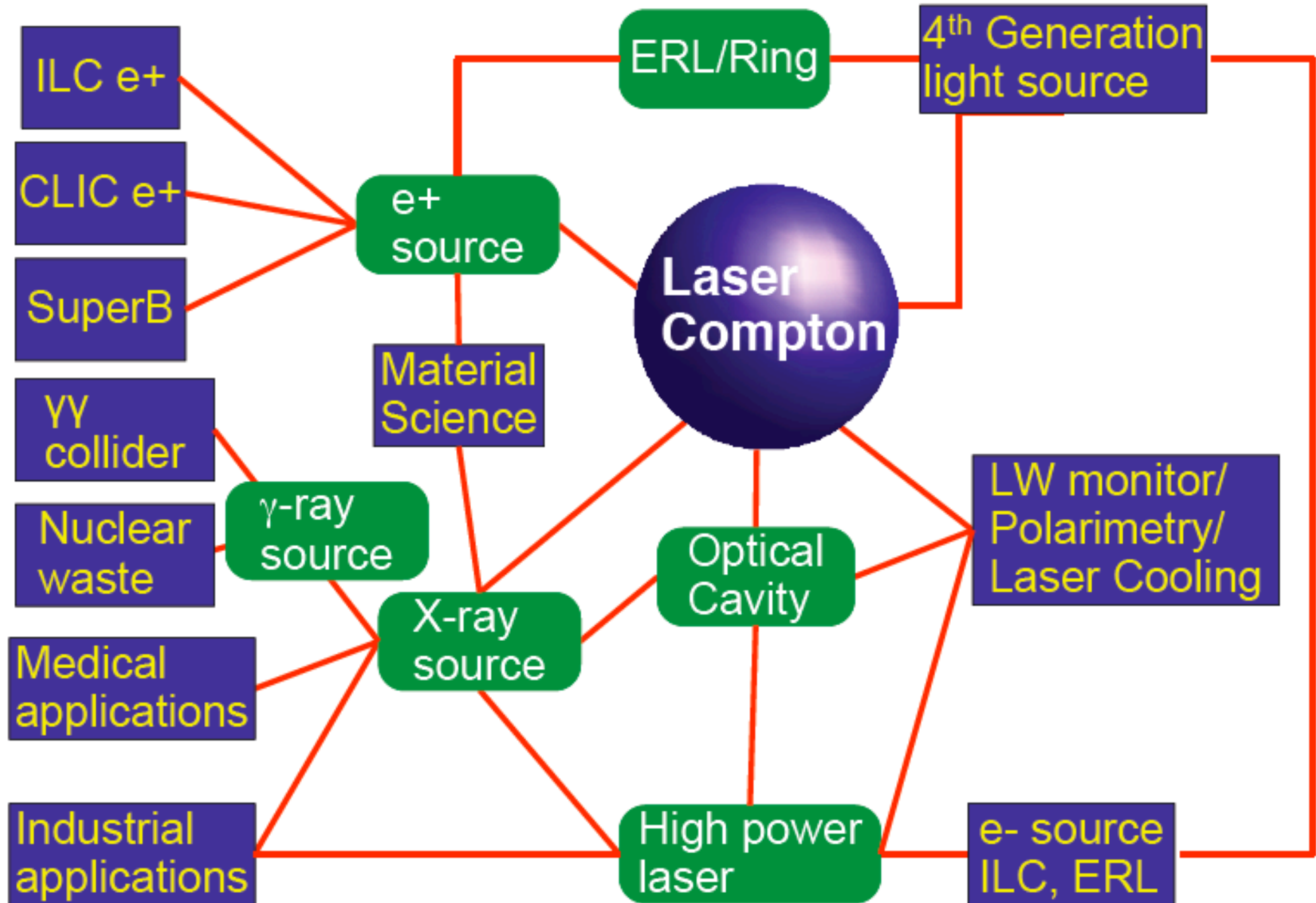
4-mirror cavity (LAL)



**high enhancement
small spot size
complicated control**

Applications and PosiPol Collaboration

World-Wide-Web of Laser Compton



PosiPol-Collaboration

1. Laser-Compton has a large potential as a future technology.
2. Many common efforts can be shared in a context of various applications.
 - Compact and high quality X-ray source for industrial and medical applications
 - γ -ray source for disposal of nuclear wastes
 - Beam diagnostics with Laser
 - Laser Cooling
 - Polarized Positron Generation for ILC and CLIC
 - $\gamma\gamma$ collider

Q-Beam and cERL (1)

- ▶ **Quantum-Beam project is a strategic R&D for X-ray source for various applications based on the SC linac.**
- ▶ **1st step: Pulsed X-ray generation with SC linac; It will be carried out at KEK-STF, 2010-2011.**
- ▶ **2nd step: CW X-ray generation with SC ERL; It will be carried out at cERL-KEK, 2012~.**

Energy : 25-30 MeV

Micro pulse rep.:162.5MHz,

Current in macro pulse:16mA,

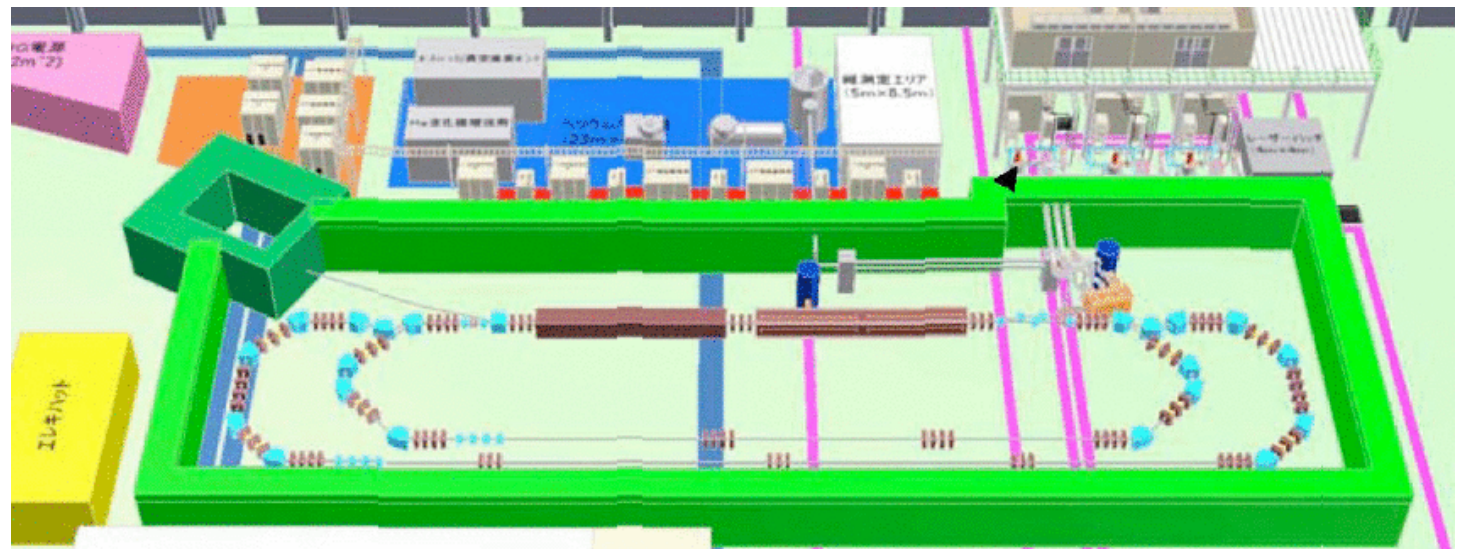
Macro pulse rep: 10Hz

<http://kocbeam.kek.jp/project/index.html>



Q-Beam and cERL (2)

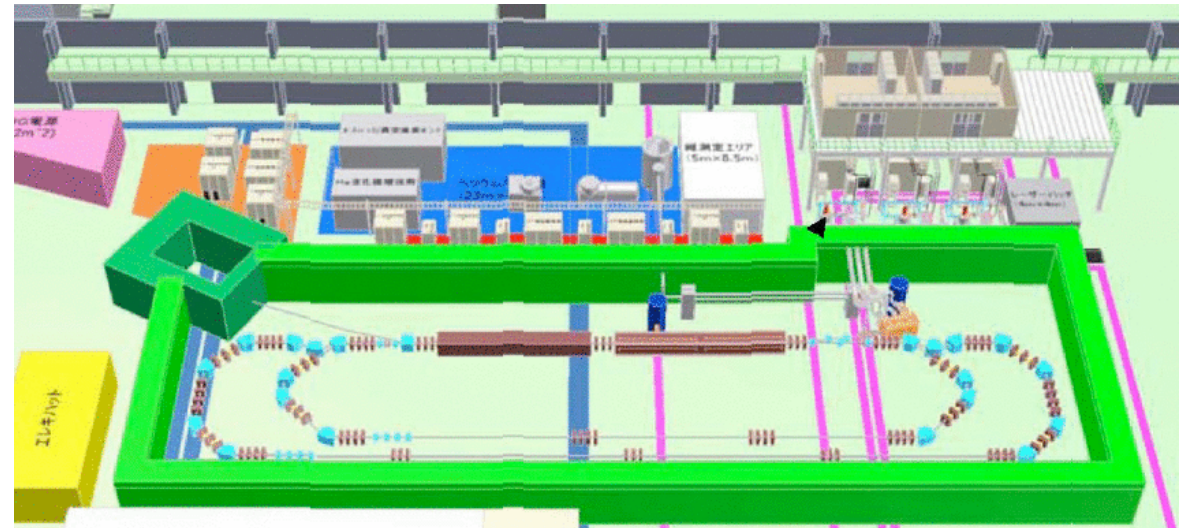
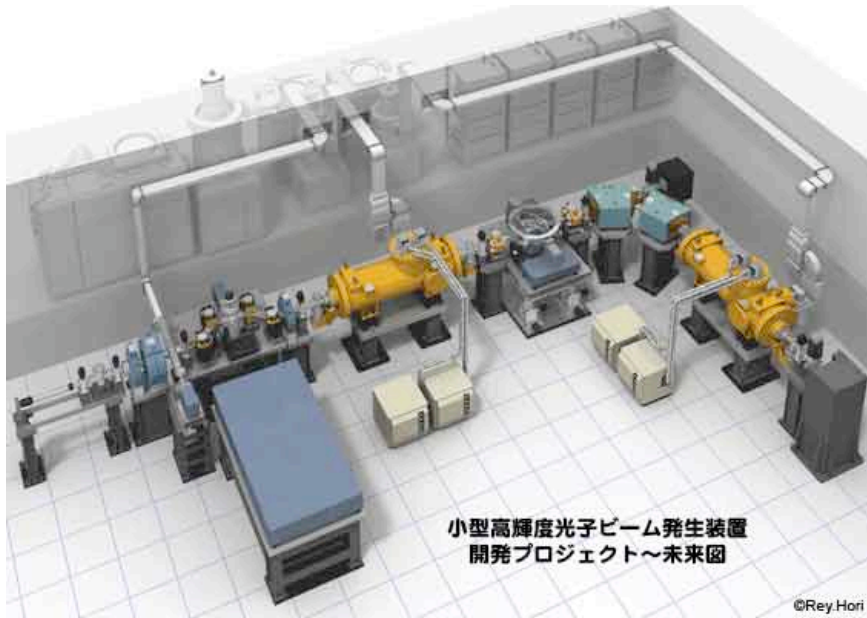
- ▶ **cERL** is a test machine to prove the technical feasibility of 5GeV class ERL machine for future light source.
- ▶ It will be constructed in the "east counter hall" of ex-KEK-PS.
- ▶ The operation will be started from 2012.
 - The energy 35-65 MeV.
 - Average current : 10mA
 - Emittance : 1.0π mm.mrad

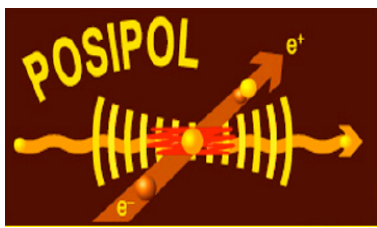


Q-Beam and cERL (3)

- ▶ Q-beam and cERL is technically very close to each other.
- ▶ X-ray generation and THz radiation are two major applications of cERL. It can be linked to the LC positron R&D.

Transition from Pulse to CW
x60 larger average current





World-wide PosiPol Collaboration

Collaborating Institutes:

**BINP, CERN, DESY, Hiroshima, IHEP, IPN, KEK,
Kyoto, LAL, CELIA/Bordeaux, NIRS, NSC-KIPT,
SHI, Waseda, BNL, JAEA and ANL**

**Sakae Araki, Yasuo Higashi, Yousuke Honda, Masao Kuriki, Toshiyuki Okugi, Tsunehiko Omori,
Takashi Taniguchi, Nobuhiro Terunuma, Junji Urakawa, Yoshimasa Kurihara, Takuya Kamitani,
Yoshisato Funahashi, X. Artru, M. Chevallier, V. Strakhovenko, Eugene Bulyak, Peter Gladkikh,
Klaus Meonig, Robert Chehab, Alessandro Variola, Fabian Zomer, Alessandro Vivoli, Richard Cizeron,
Viktor Soskov, Didier Jehanno, M. Jacquet, R. Chiche, Yasmina Federa, Iryna Chaikovska, Eric Cormier,
Louis Rinolfi, Frank Zimmermann, Kazuyuki Sakaue, Tachishige Hirose, Masakazu Washio,
Noboru Sasao, Hirokazu Yokoyama, Masafumi Fukuda, Koichiro Hirano, Mikio Takano,
Tohru Takahashi, Hirotaka Shimizu, Shuhei Miyoshi, Yasuaki Ushio, Tomoya Akagi, Akira Tsunemi,
Ryoichi Hajima, Li Xiaoping, Pei Guoxi, Jie Gao, V. Yakinenko, Igo Pogorelsky, Wai Gai, and Wanming Liu**

**POSIPOL 2006
CERN Geneve
26-27 April**

<http://posipol2006.web.cern.ch/Posipol2006/>

**POSIPOL 2008
Hiroshima
16-18 June**

<http://home.hiroshima-u.ac.jp/posipol/>

**POSIPOL 2010
KEK Tsukuba
31 May - 2 June**

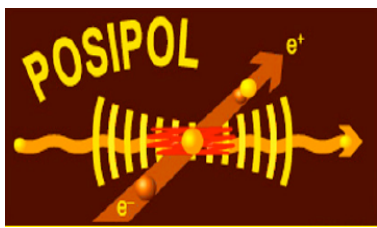
<http://atfweb.kek.jp/posipol/2010/>

**POSIPOL 2007
LAL Orsay
23-25 May**

<http://events.lal.in2p3.fr/conferences/Posipol07/>

**POSIPOL 2009
Lyon
23-26 June**

<http://indico.cern.ch/internalPage.py?pageId=1&confId=53079>



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Takashi Taniguchi, Nobuhiro Terunuma, Junji Urakawa, Yoshimasa Kurihara, Takuya Kamitani,
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Tohru Takahashi, Hirotaka Shimizu, Shuhei Miyoshi, Yasuaki Ushio, Tomoya Akagi, Akira Tsunemi,
Ryoichi Hajima, Li Xiaoping, Pei Guoxi, Jie Gao, V. Yakinenko, Igo Pogorelsky, Wai Gai, and Wanming Liu**

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16-18 June**

<http://home.hiroshima-u.ac.jp/posipol/>

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KEK Tsukuba
31 May - 2 June**

<http://atfweb.kek.jp/posipol/2010/>

**POSIPOL 2007
LAL Orsay
23-25 May**

<http://events.lal.in2p3.fr/conferences/Posipol07/>

**POSIPOL 2009
Lyon
23-26 June**

<http://indico.cern.ch/internalPage.py?pageId=1&confId=53079>

**POSIPOL 2011
IHEP Beijing
26-28 September**

Summary

Summary 1

1. Laser Compton e^+ source is attractive option for ILC/CLIC

Independent system

high polarization

5 Hz polarization flip (for CLIC 50 Hz flip)

Operability

wide applications

2. Three schemes are proposed

Ring Laser Compton for ILC

ERL Laser Compton for ILC

Linac Laser Compton

My talk Today

3. Ring & ERL Schemes

Examples of parameter sets are presented for ILC and CLIC. However, those are only examples. We absolutely need more study to get conclusions.

Summary 2

4. We need many R/Ds

- (a) e^+ stacking, (b) Ring, (c) ERL, (d) e^+ capture
- (e) e^+ production target, (e) Laser
- (g) Laser stacking optical cavity

All of R/Ds are very important and correlated.

Choices are highly depends on the results of the R/Ds.

5. We have the world-wide collaboration for Compton.

Not only for ILC/CLIC e^+ source.

Also for many other applications.

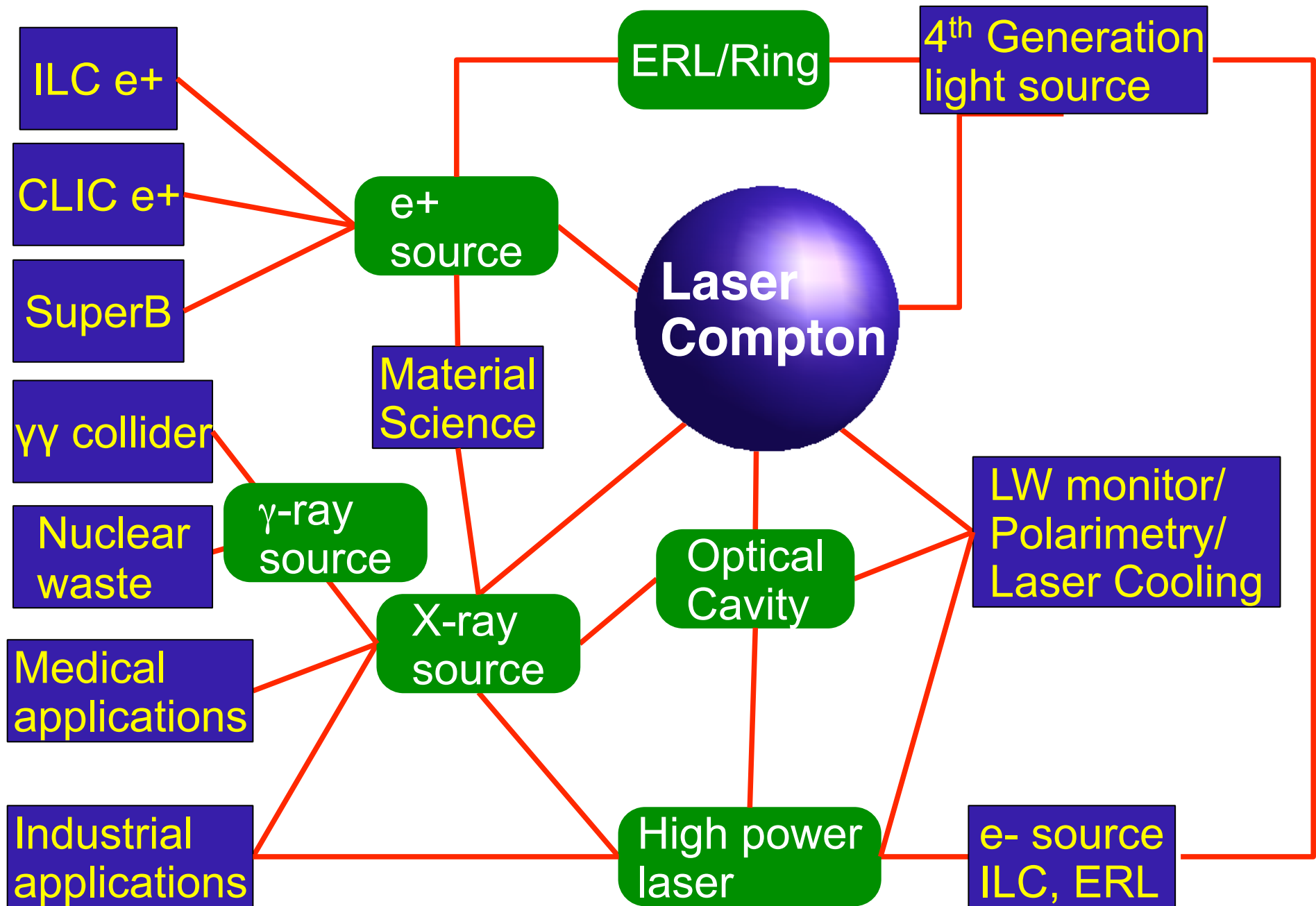
X-ray generation, treatment of nuclear waste, ERL,,,,

In KEK, Quantum beam (SRF Linac + Compton) and

cERL (Compact ERL + Compton) projects are on going.

Backup Slides

World-Wide-Web of Laser Compton



Parameters and Choices of Ring/ERL scheme

Ring Scheme Parameters

Compton Scheme Parameters

Burst Operation of Laser

Need to cool Compton Ring

Good for stacking in DR

Cooling time ~ 10 m sec

$N_g / \text{bunch} = 2.3 \times 10^{10}$ CAIN

$E = 1.8$ GeV, 0.6 J x 5 CP (assume)

$N_e / \text{bunch} = 3.3 \times 10^{10}$ (5.3 nC / bunch) (assume)

Bunch length ~ 1 p sec (assume)

$N_{e+} / \text{bunch} = 2 \times 10^8$

$N_{e+}(\text{captured}) / N_g = 0.8 \%$ (assume)

We need 100 times of stacking in a same DR bunch.

{10 stacking ($\ll 1$ ms) + cooling (~ 10 ms) } x 10

Burst Operation of Laser --> Burst Amplifier ?

Compton Scheme Parameters

Bunch Length in the Compton Ring

Bunch Length 30 p sec --> Loose luminosity

Short Bunch ?

Bunch Compress --> CPs --> Decompress
too difficult ?

Very Small Momentum Compaction Factor
beam dynamics

Crab Crossing ?

Head on Collision?

We need mirrors with a hole.

--> Non Stacking Laser Cavity --> Linac Scheme

Ne / bunch

Ne / bunch = 3.3×10^{10} (5.3 nC/bunch)

Reasonable Feasibility?

ERL Scheme Parameters

ERL repetition ($R_{\text{rep}} = 1/T_{\text{b_to_b}}$)

ERL repetition and e⁺ Stacking

How many stacks do we need ?

Number of gamma-rays

$$N_g / \text{bunch} = 0.75 \times 10^{10} \quad \text{CAIN}$$

$$E=1.8 \text{ GeV}, 0.6 \text{ J} \times 5 \text{ CP}, N_e=1 \times 10^{10}$$

Number of positrons

$$N_{e^+}(\text{captured}) / N_g = 0.8 \% \quad (\text{assume})$$

$$N_{e^+} / \text{bunch} = 0.6 \times 10^8$$

I = 26 mA (assume)

R_{rep} (MHz)	160	54	16
N_e /bunch	1×10^9	3×10^9	1×10^{10}
Necessary N stack	3300	1000	330

ERL repetition ($R_{\text{rep}} = 1/T_{\text{b_to_b}}$) continued

ERL repetition and e+ Stacking (continued)

Max N stack is limited by time.

$$T_{\text{stack}} < 100 \text{ m sec}$$

$$T_{\text{stack}} = 3000 \text{ bunches} \times N_{\text{stack}} / R_{\text{rep}}$$

I = 26 mA (assume)

R_{rep} (MHz)	160	54	16
Ne /bunch	1×10^9	3×10^9	1×10^{10}
Necessary N stack	3300	1000	330
Max N stack	5000	1600	500

Max N stack is limited by DR.

How many stacks can we achieve ?

--> Need study

ERL repetition ($R_{\text{rep}} = 1/T_{\text{b_to_b}}$) continued

ERL repetition and Laser

R_{rep} (MHz)	160	54	16
L cavity (round trip)	1.9	5.6	19
L cavity (4 mirror)	0.46	1.4	4.6

Reasonable size of stacking cavity?

Reasonable size of laser oscillator?